

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 10/733,201  
Filing Date ..... December 9, 2003  
Confirmation No. .... 5994  
Inventor ..... Garo J. Derderian et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 1762  
Examiner ..... Kelly M. Stouffer  
Attorney's Docket No. .... MI22-2402  
Customer No. .... 021567  
Title: Atomic Layer Deposition Method of Depositing an Oxide on a Substrate

**RESPONSE TO SEPTEMBER 28, 2007 FINAL OFFICE ACTION**  
**PRELIMINARY AMENDMENT TO ACCOMPANY RCE FILING**

To: Mail Stop RCE  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
601 West First Avenue, Suite 1300  
Spokane, WA 99201-3828

Responsive to the Final Office Action dated September 28, 2007, Applicant  
amends and remarks as follows:

**AMENDMENTS**